



# Finite Element analysis in X-ray optical systems

Grenoble, France 24 - 25 February 2009



**ESRF** 

## Introduction



## X-ray optics

- Monochromator crystal
- First mirror (HHL)
- Bent focusing mirror (KB, ...)
- Compound refractive lens (CRL)
- Sagittal focusing mirror
- Piezo bimorph mirror
- Bending devices



• Design, Manufacturing, Mounting, Operation

## Data for

- Ray-tracing
- Dynamic diffraction simulation



## Analyses

- Cooling and geometry optimization
- Thermal deformation
- Performance vs heat load
- Thermal stress analysis
- Surface shape and profile optimization
- Mechanical stress analysis
- Performance vs energy tuning (bending forces)
- Bent shape
- Multi-electrodes application (gap, voltage distribution)

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## Mirror - FE model (ID20 mirror)





Geometry of the mirror LX WX I	1000x/0x30	
Absorbed power	50	W
Primary slits HxV	1.5x0.8	mm <sup>2</sup>
Grazing angle	3.5	mrad
Side cooling by water at 290 K		

footprint	
<b>0.8 mm</b>	as defined

1998

## Mirror - FEA results (ID20 mirror)







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## Monochromator crystal - FEA vs Test results



- Channel-cut Si crystal monochromator
- Liquid nitrogen cooling from 2 sides
- Beam size 10.35 mm (H) × 2.3 mm (V)
- Bragg angle 14°
- Heat load from undulators U46 + U17: Gaussian distribution, volume absorption





$$FWHM_{c} = \sqrt{\left(\theta_{th} + \theta_{0}\right)^{2} + FWHM_{intr}^{2}}$$

- Good agreement between the calculation and experimental results
- Local minimum in thermal slope error

Zhang L. et al., *JSR* (2003). 10, 313-319

## Monochromator crystal - FEA results



# Thermal slope error versus absorbed power in 4 different cooling coefficients $(W/m^2/^{\circ}C)$



- Slope error independent of the cooling coefficient in the linear region
  direct cooling (high h) is not always necessary
- Slope error varies significantly with the cooling coefficient in the non-linear region

#### Slope ~ P curve can be divided into 3 regions:

- Linear region : *slope ~ P*
- Transition region : a local minimum
- Non-linear region : slope ~ P 4.6

# Piezoelectric active mirror





Zhang L., Labergerie D. and Susini J., Proceedings *STRUCOME* (1994), 371-379

Susini J., Labergerie D. and Zhang L., *RSI* (1995), **66**, 2229-2231

- Piezoelectric bimorph: spherical shape
- Active mirror
  - Spherical shape (mono-electrode)
  - Toroidal shape (multi-electrodes)
  - Active: variation of the radius of curvature by changing electric voltage
- FEA key points
  - electrode distribution, gap effects for a required shape
  - Piezoelectric matrix, elastic coefficient matrix

#### Comparison with experiments



## Piezoelectric active mirror (2)





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## Bending devices - Flexor bender





- evaluate bending forces
- Simulate the performance

$$\frac{d^2 z}{dx^2} = \frac{h}{EI} \left( \frac{(F_1 + F_2)}{2} (1 - \delta) + (F_2 - F_1) \frac{x}{L} (1 - \delta_x) \right)$$

Zhang L. et al., *JSR* (1998). 5, 804-807

## Bending devices - Flexor bender (2)





- 2 different bending moments / rectangular mirror → 1/R(x) ~ P1(x) linear function of x
- Rotation axis should be on the neutral plane of the mirror – to avoid bending capability loss

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## Sagittal focusing crystal - anticlastic deformation ~ ribs







Anti-clastic radius R, of 3 crystals : flat, 2-rib, 54-rib



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# Compound Refractive Lens - failure analysis



- Beryllium CRLs installed in 1997 in FE
- → CRL with 4 holes of 1mm in diameter to focus 8 keV X-ray beam
- bonded to a water cooled copper block
- Failure observed on Dec-2003: sudden change of focusing capability



Zhang L. et al., *Proc. of SPIE* (2004). **5539**, 48-58



FEA results:<br/> $T_{max}$ =873 °CTotal absorbed power: 139 W (-20% ?)<br/>Cooling coefficient  $h_{eff}$ =0.005 W/mm²/°C $\sigma^{VM}_{max}$ =564 MPa  $\rightarrow$  high stress, large plastic deformation<br/>thermal fatigue failure

#### Phase contrast images

Damaged lens



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# CRL - Design optimization







		present	optimized
width	mm	2	10
† <sub>thin</sub>	mm	0.1	0.2
V <sub>bm</sub>	mm	4	2
h <sub>eff</sub>	W/mm² /°C	0.005	0.02
T <sub>max</sub>	°C	873	199
σ <sup>VM</sup> max	МРа	564	205

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# CRL / Transfocator - cooling design









#1 Be CRL for ID11:thk=15um, hcv=1.E-03 W/mm2/C, Pabs=0.56 W



- N number of parabolic lenses (Be, Al, ..., 15um, 0.56, 1.4W)
- Cooled or not cooled ?
- How cooled ?



#### • Outer ring cooling

2007

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# **KB** mirror profile optimization



#### Grazing angle $\theta$ =8mrad



- > Aspheric shape: R(x) varies strongly with x
- > Highly bent :
  - Radius of curvature reaches *R<sub>min</sub>*=11.2m at x=28mm
  - Slope of bent mirror in the range of a few of mrad



- > Which profile of the mirror ?
- How to determine the profile ?

2008

# KB mirror profile optimization - algorithm



**A**)



#### From beam theory:

$$W(x) = \frac{\frac{1}{2}(F_1 * L_{arm-1} + F_2 * L_{arm-2}) + (F_2 * L_{arm-2} - F_1 * L_{arm-1}) * \frac{x}{L}}{\frac{1}{12}E * t^3 * \frac{1}{R(x)}}$$

- 1. Initial width calculated by Eq.(A):  $W_1(x)$
- 2. bent mirror shape calculated by FEA as well as curvature along the axis x on the mirror surface  $f_n(x) = d^2 U/dx^2$
- 3. Comparison with ideal shape  $f_{ref}(x) = 1/R(x)$
- 4. Correction of the mirror width as :

$$W_{n+1}(x) = W_n(x) * \frac{f_n(x)}{f_{ref}(x)}$$
 (B)

# 5. 4~5 iterations (repeat steps 2-4) give stabilized results

## KB mirror profile optimization - results





Residual slope error of 3 profiles (HFM: p=36m, q=83mm, θ=8 mrad, F1=F2=16N) 80 60 Beam theory ∆slope(FEA -ref) (urad) FEA-opt 40 Proposed 20 0 -20 -40 -60 -80 -30 -20 -10 10 0 20 30 x (mm)

Residual slope error of mirrors with 3 profiles (HFM: p=36m, q=83mm,  $\theta=8$  mrad, F1=F2=16N)



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### FEA deals with following issues:

- Mirror width profile
- Residual slope error
- Sensitivity to the uncertainty of preload spring parameters
- Si crystal orientation
- Stress in the mirror
- Resolution requirement for the Pico motors
- Stress in the bender and glue layers
- Error analysis
- Mirror performance at different photon energy

• ...





## FEA

- Widely used in X-ray optic Design, manufacturing and operation
- Providing data for
  - Ray-tracing
  - Dynamic diffraction simulation